



2621

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q56532

Hideya TAKEO

Appln. No.: 09/489,846

Group Art Unit: 2621

Confirmation No.: 6337

Examiner: Ryan J. Miller

Filed: January 24, 2000

For: **ABNORMAL PATTERN DETECTION PROCESSING METHOD AND SYSTEM**

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner for Patents
Washington, D.C. 20231

#26A
DRUM
1-14-03

Sir:

In response to the Office Action dated October 9, 2002, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Please enter the following amended paragraphs.

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Technology Center 2600

Paragraph bridging pages 4 and 5:

A. The present applicant has also proposed an abnormal pattern detection processing system which is well suited for configuring abnormal pattern detection processing as a device independent of the QAWS and constructing a network (Japanese Unexamined Patent Publication No. 2000-126163). This abnormal pattern detection processing system comprises an image selector means which selects, among the items of image information which are inputted from an image input device equivalent to the above-mentioned image forming modality, being provided with supplementary information which allows identification of the type of subject and the